



Micromachines

an Open Access Journal by MDPI

CiteScore: 7.1

Indexed in PubMed

Impact Factor: 3.5

Special Issue Reprint

MEMS/NEMS Devices and Applications, 2nd Edition

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This Reprint presents recent advances in nanoelectromechanical system (NEMS)- and microelectromechanical system (MEMS)-based devices and their applications. The collected articles cover the design, fabrication, characterization, and application of various MEMS/NEMS-based devices, including physical sensors, chemical sensors, biosensors, gas sensors, optical sensors, flow sensors, actuators, resonators, switches, micromirrors, and energy harvesters. The contributions highlight the rapid development of MEMS/NEMS technologies for miniaturized, high-performance, and low-power microsystems. The published works also demonstrate the integration of advanced materials, microfabrication techniques, and CMOS-compatible processes for emerging sensing and actuator applications. This Reprint provides researchers, engineers, and graduate students with an overview of the current trends and future directions in MEMS/NEMS technologies and their multidisciplinary applications.

